

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

(Attorney Docket No. MIC-58DV2)

Inventor:

Zhang et al.

Examiner:

Mohamedulla

Serial No.

09/722,400

Art Unit:

1756

Filing Date: November 27, 2000

For:

POLYIMIDE AS A MASK IN VAPOR HYDROGEN FLUORIDE

ETCHING

CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

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RESPONSE TO FINAL OFFICE ACTION

In the final office action dated September 17, 2003, the Examiner (1) rejected Claims 34, 38 and 46 under 35 U.S.C. §102(e) as being anticipated by U.S. Patent No. 5,922,623 issued to Tsutsui et al. ("Tsutsui"), (2) rejected Claims 39 and 50 under 35 U.S.C. § 103(a) as being unpatentable over Tsutsui, (3) rejected Claims 9, 11, 27, 28, 29, 31-33, 35, 36, 40, 42, 44, 45, 47 and 48 under § 103(a) as being unpatentable over Tsutsui in view of U.S. Patent No. 5,286,679 issued to Farnworth et al. ("Farnworth"), and (4) rejected Claims 9, 10, 12, 27, 30-33, 35, 37, 40, 43-45, 47 and 49 under § 103(a) as being unpatentable over Tsutsui in view of U.S. Patent No. 5,653,619 issued to Cloud et al. ("Cloud"). Reconsideration and allowance of the application are requested.

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